

Abstract

The present invention relates to a film formation apparatus for forming thin films having high gas barrier performance, such as a DLC (Diamond Like Carbon) film, SiO_x film, SiOC film, SiOCN film, SiN_x film, and AlO_x film, on the inner surface and/or outer surface of containers such as PET bottles. The film formation apparatus is provided with: a vacuum chamber for forming, in a vacuum state, a film on a surface of a container (4) using a heat generating element (21); a vacuum evacuation device for vacuumizing the vacuum chamber; and a relative shifting device for relatively shifting the container (4) and the heat generating element (21) in the vacuum chamber after starting vacuumization of the vacuum chamber.